



Metrics Japan TC Chapter Meeting Summary and Minutes

Japan Standards Summer 2018 Meetings

Tuesday, July 31, 2018, 15:15 – 17:00

SEMI Japan office, Tokyo, Japan

TC Chapter Announcements

Next TC Chapter Meeting

TBD (December in conjunction with SEMICON Japan 2018)

Tokyo Big Sight, Tokyo, Japan

Table 1 Meeting Attendees

Italics indicate virtual participants

Chair: Mitsune Sakamoto (ZAMA Consulting)

SEMI Staff: Chie Yanagisawa (SEMI Japan)

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Daihen	Ishii	Akira	Tokyo Electron Miyagi	Yamada	Norikazu
<i>Hitachi High-Technologies</i>	<i>Yamamoto</i>	<i>Koichi</i>	ZAMA Consulting	Sakamoto	Mitsune
Tokyo Electron	Mashiro	Supika	SEMI Japan	Yanagisawa	Chie

Table 2 Leadership Changes

<i>WG/TF/SC/TC Name</i>	<i>Previous Leader</i>	<i>New Leader</i>
None		

Table 3 Committee Structure Changes

<i>Previous WG/TF/SC Name</i>	<i>New WG/TF/SC Name or Status Change</i>
None	

Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
None		

Note 1: **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

Note 2: **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 5 Activities Approved by the GCS prior to the Originating TC Chapter meeting

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
None			

Table 6 Authorized Activities

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

#	SC/TF/WG	Details
None		

Note 1: SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsba1.nsf/TFOFSNARF>

Table 7 Authorized Ballots

#	When	TF	Details
None			

Table 8 SNARF(s) Granted a One-Year Extension

#	TF	Title	Expiration Date
None			

Table 9 SNARF(s) Abolished

#	TF	Title
None		

Table 10 Standard(s) to receive Inactive Status

Standard Designation	Title
	*There is no published Standards originated by the Japan TC Chapter.

Table 11 New Action Items

Item #	Assigned to	Details
None		

Table 12 Previous Meeting Action Items

Item #	Assigned to	Details
None		

1 Welcome, Reminders, and Introductions

Mitsune Sakamoto (ZAMA Consulting) called the meeting to order at 15:15. The meeting reminders on antitrust issues, intellectual property issues and holding meeting with international attendance were reviewed. Attendees introduced themselves.

Attachment: 01_Required_Elements_Reg_20150327_E+J

2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

Motion:	To approve the previous meeting minutes as written.
By / 2nd:	Akira Ishii (Daihen) / Norikazu Yamada (Tokyo Electron Miyagi)
Discussion:	None
Vote:	3 in favor and 0 opposed. Motion passed.

Attachment: 02_ 20180518_Metrics-Japan_MeetingMinutes_Final

3 Liaison Reports

3.1 Metrics Europe TC Chapter

Chie Yanagisawa (SEMI Japan) reported for the Metrics Europe TC Chapter there is no update.

3.2 Metrics North America TC Chapter

Chie Yanagisawa (SEMI Japan) reported for the Metrics North America TC Chapter as attached. Of note:

- RF Measurements TF
 - Future Activities
 - Review existing RF related standards: SEMI E113, E114, E115, E136, E143;
 - Load transient tests
 - Reliability/ Availability of RF Generator/ RF supply system
 - Application of E10 like metrics
 - Measurements, particularly modulation (e.g., RF measurements on modulated loads)
 - Measurement accuracy, definitions
 - Pulsing, Frequency Sweep, Arc Management
 - + Issues/topics raised during revision to E135 that were not yet incorporated

Supika Mashiro added an explanation about the new task force with the leadership of herself as below, which was approved by the NA TC Chapter at the TC Chapter meeting held on July 11, 2018.

- TF name
 - Critical Chamber Components (CCC) Test Methods Task Force
- Charter
 - To ensure the critical chamber components (CCC) are suitable for being used for the type of production equipment and process application they are designed to be used in semiconductor device manufacturing

- To establish Test methods for ensuring that each critical non-process performance related characteristic of CCC is measured, recorded and reported in a uniform manner for better quality assurance and traceability in the event of process failure/defects increase.
- Scope:
 - To develop Test Methods for measuring different type of contaminants (e.g., metals, particles, organics) on the wetted area of critical chamber components (CCC).
 - To develop Test Methods for measuring surface morphology of CCC
 - To develop or expand existing Standards to address Test Methods for refurbished CCC parts.
 - May expand other characteristics of CCC as far as such characteristics are in common for across different process equipment types and/or models

Attachment: 03_NA Metrics Report July 2018_v1

3.3 SEMI Staff Report

Chie Yanagisawa (SEMI Japan) gave the SEMI Staff Report as attached. Items are:

- SEMI Global 2018 Calendar of Events
- Global Standards Meeting Schedule
- 2018 Critical Dates for SEMI Standards Ballots
- A&R Ballot Review
- SEMI Standards Publications
- Regulations & Procedure Manual Changes
- JRSC Topics
- Standards Topics for SEMI Japan News letter

Attachment: 04_SEMI Staff Report 20180718_v1.1

4 Ballot Review

None

5 TF/SG Report

5.1 ESD/ESC Task Force

Chie Yanagisawa (SEMI Japan) reported for the task force that there has been no activity.

5.2 International Environmental Contamination Control (ECC) Task Force

Chie Yanagisawa (SEMI Japan) reported for the task force that there has been no activity.

5.3 Japan RF Measurement liaison Task Force

Supika Mashiro (Tokyo Electron) reported for the task force as attached.

Attachment: 05_JA_RF Measurement LTF_20180731_rev0.1

6 Old Business

None

7 New Business

None

8 Action Item Review

8.1 Open Action Items - None

8.2 New Action Items - None

9 Next Meeting and Adjournment

The next meeting is tentatively scheduled as follows. See <http://www.semi.org/en/events> for the current list of meeting schedules.

- Date: TBD (December in conjunction with SEMICON Japan 2018)
- Place: Tokyo Big Sight, Tokyo, Japan

Having no further business, a motion was made to adjourn. Adjournment was at 17:00.



Respectfully submitted by:

Chie Yanagisawa

Manager

SEMI Japan

Phone: +81.3.3222.5863

Email: cyanagisawa@semi.org

Minutes tentatively approved by:

Mitsune Sakamoto (ZAMA Consulting), Chair	August 8, 2018
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Table 13 Index of Available Attachments^{#1}

<i>Title</i>	<i>Title</i>
01_Required_Elements_Reg_20150327_E+J	04_SEMI Staff Report 20180718_v1.1
02_20180518_Metrics-Japan_MeetingMinutes_Final	05_JA_RF Measurement LTF_20180731_rev0.1
03_NA Metrics Report July 2018_v1	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.